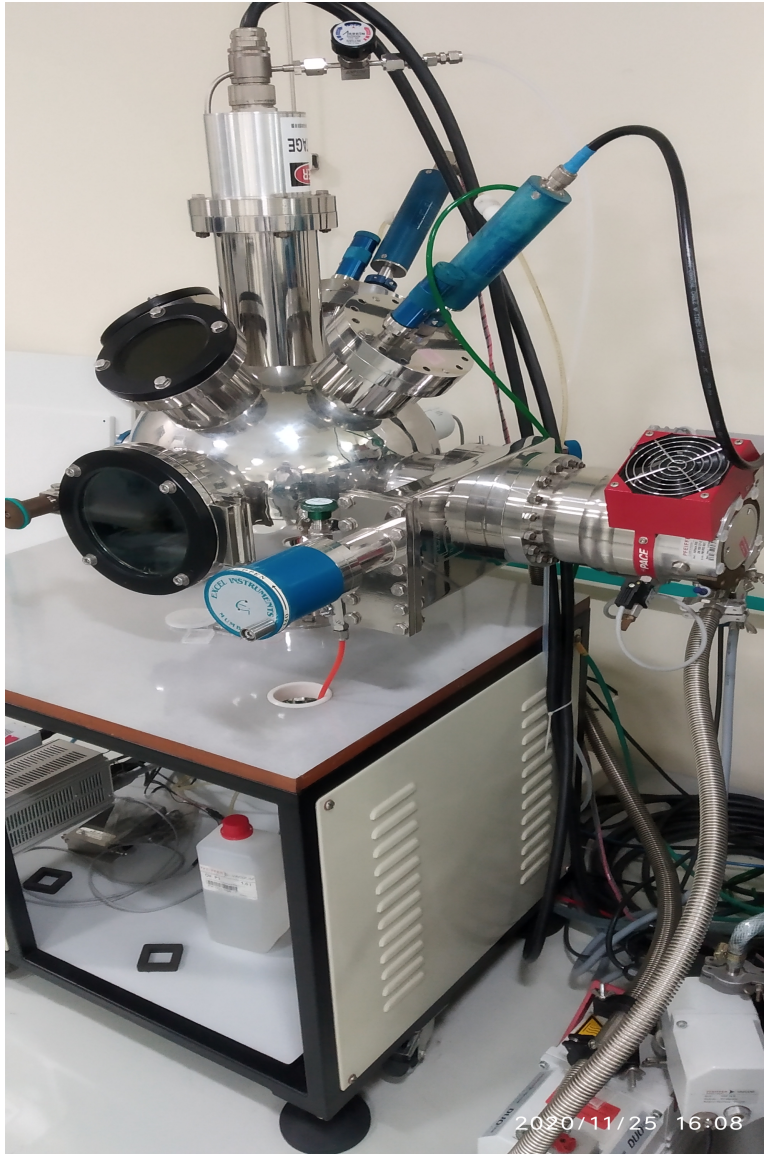


Ar-ion Milling usage policy



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Allowed Materials

1. All metals are allowed.
2. All oxide thin films are allowed however ZnO, Bismuth composites, Na and K containing films are not allowed.

Procedure to obtain System Training and Authorization

1. Training request should be sent using IITBNF equipment request interface
2. As a part of training, the student should attend 1 demo session and 3 complete hands-on in presence of assigned AU/SO.
3. Authorization test will be taken after all training modules get completed.
4. The student needs to perform one complete run in presence of SO.

Violation Policy

1. If a user violates any of the SOP steps, leading to system/KRI source down-time then his Authorization will be revoked immediately and depending upon severity of mistake he/she may be asked to appear for further punishment decided by DAC committee.
2. User should not fail to make log-book entry of process run.
3. Users should not make system hardware changes without discussing it with the FIC/SO.
4. Severe violations will make users barred from using the system for up to 2 months.

Re-authorization Policy

1. If a user has not used the system for more than 3 months at a stretch, he/she will need to clear the authorization test again to resume system usage.